

IN THE CLAIMS

Please amend the claims as follows:

1    1 (Currently Amended). A microphotonic device comprising:

2                a flexible membrane structure that can experience strain; and

3                a waveguide element formed on said flexible membrane structure so that when

4        said flexible membrane structure is strained, said waveguide element is tuned to a

5        selective amount.

1    2 (Currently Amended). The microphotonic device of claim 1, wherein said flexible

2        membrane structure comprises a sub-micron SiO<sub>2</sub> layer.

1    3 (Original). The microphotonic device of claim 1, wherein said waveguide element

2        comprises a microring resonator.

1    4 (Original). The microphotonic device of claim 1, wherein said waveguide element

2        comprises a microracetrack resonator.

1    5 (Original). The microphotonic device of claim 1, wherein said waveguide element

2        comprises a 1-dimensional photonic crystal.

1    6 (Original). The microphotonic device of claim 1, wherein said waveguide element

2        comprises a 2-dimensional photonic crystal.

1    7 (Original). The microphotonic device of claim 5, wherein said 1-dimensional

2        photonic crystal comprises holes.

1 8 (Original). The microphotonic device of claim 7, wherein said selective amount  
2 comprises approximately 1%.

1 9 (Original). The microphotonic device of claim 3, wherein said selective amount  
2 comprises 0.2%.

1 10 (Currently Amended). The microphotonic device of claim 1 further comprising at  
2 least one piezoelectric actuator that is coupled to said flexible -membrane so as to  
3 produce said strain.

1 11 (Currently Amended). A method of forming a microphotonic device comprising:  
2 providing a flexible membrane structure that can experience strain; and  
3 forming a waveguide element on said flexible membrane structure so that when  
4 said flexible membrane structure is strained said waveguide element is tuned to a  
5 selective amount.

1 12 (Currently Amended). The method of claim 11, wherein said flexible membrane  
2 structure comprises a sub-micron SiO<sub>2</sub> layer.

1 13 (Original). The method of claim 11, wherein said waveguide element comprises a  
2 microring resonator.

1 14 (Original). The method of claim 11, wherein said waveguide element comprises a  
2 microracetrack resonator.

1 15 (Original). The method of claim 11, wherein said waveguide element comprises a  
2 1-dimensional photonic crystal.

1 16 (Original). The method of claim 11, wherein said waveguide element comprises a  
2 2-dimensional photonic crystal.

1 17 (Original). The method of claim 15, wherein said 1-dimensional photonic crystal  
2 comprises holes.

1 18 (Original). The method of claim 17, wherein said selective amount comprises  
2 approximately 1%.

1 19 (Original). The method of claim 13, wherein said selective amount comprises  
2 0.2%.

1 20 (Currently Amended). The method of claim 11 further comprising providing at least  
2 one piezoelectric actuator that is coupled to said flexible membrane so as to produce  
3 said strain.